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EXAMINER

PTO-1449 R	REPROD	UCED		ATTORNEY DOCKET NO.	APPLICA	TION NO.			
INFORMATION DISCLOSURE CITATION				301500.3000-106	10/662,892				
		IN AN APPLICATION 5/17/2004		APPLICANT					
		(Use several sheets if necessary)		Oleg P. Kishkovich et al.					
				FILING DATE		RT UNIT			
				September 15, 2003	2812				
U.S. PATENT DOCUMENTS EXAM-									
INER INI- TIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE		
ACI.	AD2	4,474,051	Oct 2 1984	Fukuda et al.	73	19	//x		
	AE2	5,054,046	Oct 1 1991	Shoulders	378	119			
	AF2	5,153,901	Oct 6 1992	Shoulders	378	119			
	AG2	5,168,068	Dec 1 1992	Yanagisawa et al.	436	134			
1	AH2	6,168,948	Jan 2 2001	Anderson et al.	435	287.2	1/\sqrt{3}		
1	AI2	5,481,110	Jan 2 1996	Krishnaswamy et al.	250	288	K///		
	AJ2	5,725,634	Mar 10 1998	Takasuga et al.	95	45			
	AK2	5,841,022	Nov 24 1998	Hase	73	23.22	/ //		
	AA3	5,898,114	Apr 27 1999	Basch et al.	73	863.23	XX		
	AB3	5,935,302	Aug 10 1999	Ju et al.	96	4	(X_2)		
	AC3	6,009,739	Jan 4 2000	Fujiwara et al.	73	1.02			
	AD3	6,119,532	Sep 19 2000	Park et al.	73	864.34			
	AE3	6,139,801	Oct 31 2000	Kawachi et al.	422	88			
	AF3	6,239,038	May 29 2001	Wen	438	745	1		
	AG3	6,295,864	Oct 2 2001	You et al.	73	53.01			
	AH3	6,310,356	Oct 30 2001	Yuhara et al.	250	574	XX		
	AI3	6,467,333	Oct 22 2002	Lewis et al.	73	31.05	XX		
	AJ3	6,470,760	Oct 29 2002	Shinozaki et al.	73	863.33			
	АК3	6,497,136	Dec 24 2002	Satou	73	23.22			
	AA4	6,620,630	Sep 16 2003	Kishkovish et al.	438	7	XX		
	AB4	2002/0121148 A1	Sep 5 2002	Shinozaki et al.	73	863.33	Jun 29 1999		
			FORE	EIGN PATENT DOCUMENTS					
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION YES NO		
	AO2	2 320 088	10 Jun 1998	UK patent application					
examiner July Clarityson				DATE CONSIDERED 07-08-05					

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INFO	DRMATION DISCLOSURE CITATION	301500.3000-106				
IN AN APPLICATION 5/17/2004 (Use several sheets if necessary)		APPLICANT Oleg P. Kishkovich et al.				
		FILING DATE	GROUP ART UNIT			
		September 15, 2003	2812			
98 AR						
AR AR	Ogawa & Company, company website, www.ogawausa.com, About Ogawa & Company, July 24, 2003.					
AS AS	Ogawa & Company, company website, www.ogawausa.com, Passive Sampler, July 24, 2003.					
Dallas, et al., "Characterization and Control of Organic Airborne Contamination in Lithographic Processing", Paper presented at SPIE Microlithography 2002.						
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